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Sheet 1 of 1

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Examiner Name	SARA W CRANE
Attorney Docket No.	1030681-000634

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Examiner Initials	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.
/O.N./	Sneh, Ofer et al., <i>Thin film atomic layer deposition equipment for semiconductor processing</i> , Thin Solid Films 402 (2002) 248-261
/O.N./	Copy of Office Action issued by Chinese Patent Office on March 21, 2007 for Chinese Patent Application No. 2004100283929
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